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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Granneman et al.
Appl. No. : 10/700,298
Filed : October 31, 2003
For : METHOD FOR THE HEAT
TREATMENT OF SUBSTRATES
Examiner : Christian D. Wilson

Group Art Unit 2829

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April 11, 2005

(Date)

Adeel S. Akhtar, Reg. No. 41,394

RESPONSE TO RESTRICTION REQUIREMENT**Mail Stop Amendment**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir:

In an action mailed March 14, 2005, the Examiner required restriction of prosecution to one of the following groups of claims:

- Group I Claims 1-51, drawn to a method of manufacturing a semiconductor device, classified in class 438, subclass 795; and
- Group II Claims 52-56, drawn to an apparatus for heating a substrate, classified in class 219, subclass 390.

In response to this restriction requirement, Applicants elect to proceed, without traverse, with prosecution on the merits of Group I (Claims 1-51), drawn to a method of manufacturing a semiconductor device.

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CONCLUSION

In view of the foregoing, Applicants submit that the application is in condition for examination on the merits, and respectfully request the same.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: April 11, 2005

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